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Email: iplaw@volentine.comDate: January 23, 2006To: Examiner Novacek
U.S. Patent OfficeFax No: 571-273-8300

Ph. No:

From: Andrew J. Telesz, Jr.Subject: Serial No. 10/780,867
Our Ref. No.: OKI.3900No. of Pages (including cover): 10.....
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CERTIFICATE OF TRANSMISSION BY FACSIMILE (37 CFR 1.8)Applicant(s): **Kazuya Hizawa**

Docket No.

OKI.390C

Application No.

10/780,867

Filing Date

February 19, 2004

Examiner

C. Novacek

Group Art Unit

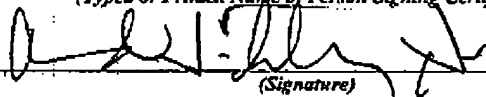
2822

Invention: **A METHOD FOR FABRICATING A SEMICONDUCTOR DEVICE HAVING A METALLIC SILICIDE LAYER**

I hereby certify that this


Request for Reconsideration*(Identify type of correspondence)*is being facsimile transmitted to the United States Patent and Trademark Office (Fax. No. 571-273-8300)

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January 23, 2006*(Date)***Andrew J. Telesz, Jr.***(Typed or Printed Name of Person Signing Certificate)**(Signature)*

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P18/REV02

TRANSMITTAL LETTER (General - Patent Pending)				JAN 23 2006 Docket No. OKI390C	
In Re Application Of: Kazuya Hizawa					
Application No. 10/780,867	Filing Date February 19, 2004	Examiner C. Novacek	Customer No. 20987	Group Art Unit 2822	Confirmation No. 1983
Title: A METHOD FOR FABRICATING A SEMICONDUCTOR DEVICE HAVING A METALLIC SILICIDE LAYER					
<u>COMMISSIONER FOR PATENTS:</u>					
<p>Transmitted herewith is:</p> <p style="margin-left: 40px;">Request for Reconsideration</p> <p>in the above identified application.</p> <p><input checked="" type="checkbox"/> No additional fee is required.</p> <p><input type="checkbox"/> A check in the amount of _____ is attached.</p> <p><input checked="" type="checkbox"/> The Director is hereby authorized to charge and credit Deposit Account No. 50-0238 as described below.</p> <p style="margin-left: 40px;"> <input type="checkbox"/> Charge the amount of _____ <input checked="" type="checkbox"/> Credit any overpayment. <input checked="" type="checkbox"/> Charge any additional fee required. </p> <p><input type="checkbox"/> Payment by credit card. Form PTO-2038 is attached.</p> <p>WARNING: Information on this form may become public. Credit card information should not be included on this form. Provide credit card information and authorization on PTO-2038.</p> <div style="display: flex; justify-content: space-between;"> <div style="width: 45%;">  Signature </div> <div style="width: 45%; text-align: right;"> <p>Dated: January 23, 2006</p> </div> </div> <div style="display: flex; justify-content: space-between;"> <div style="width: 45%;"> <p>ANDREW J. TELESZ, JR. REG. NO. 33,581</p> <p>VOLENTINE FRANCOS & WHITT, P.L.L.C. 11951 FREEDOM DRIVE, SUITE 1260 RESTON, VA 20190 TEL. NO. (571) 283-0720</p> </div> <div style="width: 45%; border: 1px solid black; padding: 5px;"> <p>I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to the "Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450" [37 CFR 1.8(a)] on _____.</p> <p style="text-align: center;">(Date)</p> <hr/> <p style="text-align: center;">Signature of Person Mailing Correspondence</p> <hr/> <p style="text-align: center;">Typed or Printed Name of Person Mailing Correspondence</p> </div> </div>					
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Serial No. 10/780,867

OKI.390C

Request for Reconsideration dated January 23, 2006

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of

Kazuya Hizawa

Group Art Unit: 2822

Serial No.: 10/780,867

Examiner: C. Novacek

Filed: February 19, 2004

Confirm No.: 1983

For: A METHOD FOR FABRICATING A SEMICONDUCTOR DEVICE HAVING A
METALLIC SILICIDE LAYER

REQUEST FOR RECONSIDERATION

U.S. Patent and Trademark Office
Customer Window, Mail Stop AF
Randolph Building
401 Dulany Street
Alexandria, VA 22314

Date: January 23, 2006

Sir:

In response to the Final Office Action dated November 8, 2005, the following
remarks are respectfully submitted in connection with the above-identified application.

Remarks/Arguments begin on page 2 of this paper.

Page 1 of 7

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